## IN THE CLAIMS

Please amend the claims as follows:

- 1. (currently amended) A method for producing a quartz glass blank, <u>said method</u> comprising: a method step in which SiO<sub>2</sub> particles are produced by [<u>means of</u>] a row of deposition burners and deposited on a cylinder outer surface of a carrier rotating about <u>a</u> [<u>the</u>] longitudinal axis thereof to form a cylindrical porous SiO<sub>2</sub> soot body, [<u>the surface temperature of the forming soot body being altered by means of</u>] a temperature adjustment body <u>altering a surface temperature of the soot body as it is being formed</u>, [<u>characterized in that</u>] <u>wherein</u> the temperature adjustment body <u>comprises</u> [<u>is used in the form of</u>] a planar element [(13; 31)] extending along a substantial part of the SiO<sub>2</sub> soot body [(2)], which either <u>acts</u> as a homogeneous heat sink <u>and</u> has a temperature-shielding effect on the soot body surface [(10)] or, <u>acts</u> as a homogeneous reflector, <u>and has</u> a temperature-raising effect due to heat radiation.
- (currently amended) The method according to claim 1, [eharacterized in that] wherein said [a] planar element [(31) is used that] is formed by an inner wall of a housing [(30)] surrounding the SiO<sub>2</sub> soot body[(2)].
- 3. (currently amended) The method according to claim 1 [or 2], [eharacterized in that] wherein the planar element [(13; 31)] acts as a reflector with a reflectance for IR radiation between 80% and 100%.
- 4. (currently amended) The method according to claim 3, [eharacterized in that] wherein heat of the deposition burners [(5)] is reflected towards the soot body [(2)] by means of the planar element [(31)].
- 5. (currently amended) The method according to claim 3, [eharacterized in that] wherein heat of the forming SiO<sub>2</sub> soot body [(2)] is reflected by means of the planar element [(13)] towards the soot body surface [(10)].

- 6. (currently amended) The method according to <u>claim 1</u> [any one of the preceding elaims], [characterized in that] wherein the planar element has an efficiency, defined as <u>a</u> [the] solid angle covering the forming SiO<sub>2</sub> soot body, of at least 60%.
- 7. (currently amended) The method according to claim 1 [or 2], [characterized in that] wherein the planar element acts as a heat sink absorbing IR radiation.
- 8. (currently amended) The method according to claim 7, [eharacterized in that] wherein the [a] planar element [is used that] has a roughened surface having a mean surface roughness R<sub>a</sub> of at least 10 μm.
- 9. (currently amended) The method according to claim 7 [or 8], [characterized in that]
  wherein the [a] planar element [is used that] has a blackened surface.
- 10. (currently amended) The method according to <u>claim 7</u> [any one of claims 7 to 9], [characterized in that] wherein the planar element is cooled.
- 11. (currently amended) The method according to claim 3 [1 and any one of claims 3 to 10], [characterized in that] wherein the planar element is moved along the soot body [2)].
- 12. (currently amended) The method according to claim 3 [1 and any one of claims 3 to 11], [characterized in that] wherein the distance between the planar element [(13)] and the surface [(10)] of the forming SiO<sub>2</sub> soot body [(2)] is kept constant.
- (currently amended) The method according to <u>claim 1</u> [any one of the preceding <u>claims</u>], [characterized in that] wherein the planar element [(13; 31)] extends over the whole usable length of the soot body [(2)].

- 14. (currently amended) A device for carrying out the method according to <a href="claim 1">claim 1</a> [any one of the preceding claims], <a href="said device">said device</a> comprising: a row of deposition burners for producing SiO<sub>2</sub> particles, a carrier which is rotatable about the longitudinal axis thereof and <a href="having a">having a</a> [on the] cylinder outer surface on [of] which the produced SiO<sub>2</sub> particles are deposited to form a cylindrical porous SiO<sub>2</sub> soot body, <a href="mailto:and-emprising">and [eomprising</a>] at least one temperature adjustment body <a href="mailto:that">that</a> [which] is [arranged] <a href="mailto:supported">supported</a> in <a href="mailto:ana-[the]">ana-[the]</a> area of the forming soot body and <a href="mailto:that">that</a> [which] acts on <a href="mailto:a-tale="mailto:that">a [the]</a> surface temperature of the forming soot body for altering an axial density profile, [eharacterized in that]</a> <a href="which">wherein</a> the temperature adjustment body comprises a planar element [(13; 31) which]</a> <a href="mailto:that">that</a> acts as a homogeneous heat sink or as a homogeneous reflector and <a href="mailto:that">that</a> [which]</a> extends along a substantial part of the SiO<sub>2</sub> soot body [(2)] and has a predetermined reflectance for IR radiation.
- 15. (currently amended) The device according to claim 14, [characterized in that] wherein the planar element [(31)] is formed by an inner wall of a housing [(30)] surrounding the SiO<sub>2</sub> soot body [(2)].
- 16. (currently amended) The device according to claim 14 [or 15], [eharacterized in that] wherein the planar element [(13; 31) for IR radiation] has a reflectance between 80% and 100% for IR radiation.
- 17. (currently amended) The device according to claim 16, [characterized in that] wherein the planar element [(13; 31)] has a concave curvature [(7; 33)].
- 18. (currently amended) The device according to claim 16 [or 17], [characterized in that] wherein the concave curvature [(33)] has a focal point [(34)] which is located in an [the] area of the row of deposition burners [(5)].

- 19. (currently amended) The device according to claim 16 [to 17], [eharacterized in that] wherein the concave curvature [(7)] comprises a focal point [(14)] which is located in the area of the forming SiO<sub>2</sub> soot body [(2)].
- 20. (currently amended) The device according to <u>claim 14</u> [any one of claims 14 to 19], [characterized in that] wherein the planar element comprises a surface absorbing IR radiation.
- 21. (currently amended) The device according to claim 20, [characterized in that] wherein the planar element is roughened and has a mean surface roughness R<sub>a</sub> of at least 10 μm.
- 22. (currently amended) The device according to claim 20 [or 21], [characterized in that] wherein the planar element has a blackened surface.
- 23. (currently amended) The device according to <u>claim 20</u> [any one of claims 20 to 22], [characterized in that] wherein the planar element is provided with a cooling device.
- 24. (currently amended) The device according to claim [14 and any one of claims] 16 [to 23], [characterized in that] wherein the planar element is supported for movement [made movable] along the soot body.
- 25. (currently amended) The device according to claim [14 and any one of claims] 16 [to 24], [characterized in that] wherein the planar element [(13)] is made displaceable in a direction perpendicular to the longitudinal axis [(3)] of the carrier.
- 26. (currently amended) The device according to <u>claim 14</u> [any one of the preceding claims 14 to 25], [characterized in that] wherein the planar element [(13; 31)] extends over the whole usable length of the soot body [(2)].